

XS-Series Semiconductor setup



High Speed Inline AXI Platform with minimal footprint

The Nordson T&I MATRIX XS-series with Semiconductor setup is an automatic inspection system platform designed for sophisticated high speed inspection of semiconductor products. Available with Class 1000 cleanroom certification, it is the perfect solution for the inspection of leadframes, substrates or singulated devices in Jedec trays. The following setups are available:

High Resolution Setup	Ultra High Resolution Setup
2,5-3 μm/pix resolution	0,8 μm/pix resolution
Gold-wires, CU-wires down to 1,5mil diameter,	Gold-wires, CU wires down to 0,6mil diameter,
die-attach voiding	die attach, $\mu\text{-bump}$ voiding and flipchip inspection of $40\mu\text{m}$ bump sizes

The Nordson MATRIX system solutions present a modular inspection concept. The platforms feature up to 4 advanced technologies in one system: Transmission X-ray imaging (2D) with patented Slice-Filter-TechniqueTM (SFT), Off-Axis technology (2.5D) and 3D Planar CT (Simultaneous Algebraic Reconstruction Technique).



XS-2 Transmission (2D) + SFT^{TM}

XS-2.5 Transmission (2D) + SFTTM + Off-Axis (2.5D)

XS-3 Transmission (2D) + SFTTM + Off-Axis (2.5D) + 3D Planar CT

Inspection & Process Software

- MIPS 5 Inspection Platform
 - Advanced algorithm library
 - CAD import for automatic inspection list generation
 - Simultaneous Algebraic Reconstruction Technique (3D Planar CT; XS-3 only)
 - Automatic Tree Classification (ATC) for Auto-Rule-Generation
 - Offline programming for inspection program generation & simulation, setup and defect reference catalogue
- Verification & Process control
 - MIPS Verify with closed loop repair
 - MIPS Process with real time SPC

Features and Benefits

- High Speed AXI system for inline setups
- Microfocus/Nanofocus X-ray tube (sealed, maintenance free)
- High-speed motion system with linear drives
- Digital CMOS flatpanel detector
- Automatic grey-level and geometrical calibration
- Flexible setup for inline pass through or same-side in/out configuration
- Full product traceability via various Industry 4.0 MES Interfaces
- SEMI S2/S8 compliance





XS-series Semiconductor setup

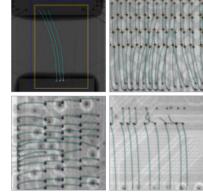
Applications

Semiconductor / Wire Bond Testing

A unique advanced algorithm library is available for the inspection of:

- Semiconductor applications
- Full wire bond Test (pre & post encapsulation)
- Multiple die inspection, up to 16 die stacks
- Flip-chip inspection
- Flex circuits
- Die-Attach Voiding

Specifications



For more information, speak with your Nordson MATRIX representative.

Germany/ Headquarters

Feldkirchen (Munich) +49.89.2000.338.200 info@nordsonmatrix.com

Hungary/Europe

+36.30.876.5038 hungary@nordsonmatrix.com

Americas

+1.760.930.3301 serviceusa@nordsonmatrix.com

South East Asia

+65.6552.7533 sea@nordsonmatrix.com

China

+86.512.6665.2008 china@nordsonmatrix.com

Japan

+81.3.3599.5920 info@nordsonmatrix.com

Korea

+82.31.736.8321 info@nordsonmatrix.com

Taiwan

+886.963.004.675 cs.taiwan@nordson.com

India

+91 44 4353902 sea@nordsonmatrix.com

Facilities		
Dimensions:	1760 mm (H) x 1300 mm (W) x 1600 mm (D)	
Weight:	2.320 kg	
Safe Operating Temperature:	15° - 28 °C optimal 20° - 25° C	
Power Consumption:	max. 6 kVA	
Line Voltage:	208 / 400 VAC, 50/60 Hz 3 phase, 24/16 A	
Air:	5-7 Bar, < 2 l/min, filtered (30µ), dry, oil free	

X-ray Image Chain		
X-ray Source (sealed tube)		
Energy:	High resolution setup 100 kV / 20 W	Ultra high resolution setup 160 kV / 20 W
Grey resolution:	14 Bit	
CMOS Flatpanel Detector	50 μm pixel size	

Motion System	
<u>Installed axes</u>	
x,y (linear drives)	sample table
z (servo)	magnification
u,v (linear drives)	detector movement
Conveyor setup	
pass through	single lane
In-out same side	dual lane

X-ray inspection setup)	
Off-Axis capability.	Angle shot capability:	up to 30 deg
FoV range:	Transmission FoV:	1.9 mm to 25 mm
Sample Inspection Parameter		
Standard setup:	Max. sample size (W x L):	200 mm x 250 mm - High Res. Setup
		150 mmx 250 mm - Ultra High Res. Setup
	Min. sample size (W x L):	> 25mm x 60mm
	Max. inspection area (Transmission):	Same as max. sample size (please see above)
Assembly Clearance	Topside (incl. board thickness):	+/- 15 mm
	Bottom side (excl. board thickness):	+/- 15 mm
	Edge clearance for clamping:	1,5 mm - 3 mm
Sample-Warpage Compensation	Optional item	Top-clamp or Vacuum Jig Technique

Inspection speed		
Transmission (XS-2, XS-2.5, XS-3)	up to 6 views /s	
Off-Axis (XS-2.5, XS-3)	up to 5 views /s	
3D Planar CT (XS-3)	up to 1 s /FoV	

Options
Automated Barcodereader station
Substrate Handling setup with Magazine loader/unloader/laser-marker
Top-clamp warpage compensation
Multiple HEPA filter configurations